

Configuration Sheet

NanoSpec® 8000x

Automated Film Thickness Measurement System

Main configuration:

- Open cassette station for 100mm, 125mm, 150mm and 200mm
- DUV-Visible Spectroscopic Reflectometry from 210 to 780 nm
- t , n and k measurements on single and multi-layer film stacks
- OS/2 operating system for real-time, multi-tasking operations
- AFT user interface

Standard Feature:

- Base unit includes one visible (4x) objective and one UV (15x) objective and one (40X) objective
- DUV to Visible reflectometer
- OS/2-based AFT metrology software
- Contrast-tolerant pattern recognition software
- Automatic focus
- Open cassette
- Dual end-effector robot
- Optical non-contact pre-aligner (centering and notch/flat finder)
- Wafer handling: backside vacuum pickup (random access)
- Joystick
- Touch Screen Monitor

Facility Requirements:

Dimensions:

- 104W x 109D x 161H (cm)
- (not including maintenance areas)

Weight:

- 750 lb. (1,150 lb. crated)
- 340KG

Install Location

- Isolated stable pad

Electrical:

- 115 VAC, 50/60 Hz, 20A

Power Cord:

- Single 10 ft., 3-conductor, 12 AWG, 600V rating

Power Outlet:

- Twist lock connection

Feed Location:

- Backside, lower right (viewed from rear)

Vacuum

- ≥ 635 mm (25 in.) Hg at 10 l/min flow rate

Line Size

- 6.35 mm (0.25 in.) OD

Connector Type

- Presslock bulkhead fitting (0.25 x 0.25 in.)

